



501.42174VX1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: R. FURUKAWA, et al.  
Application No.: 10/699,690  
Filed: November 4, 2003  
For: METHOD FOR MANUFACTURING SEMICONDUCTOR  
INTEGRATED CIRCUIT DEVICE  
Art Unit: 2818  
Examiner: Q. Hoang

**INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 CFR §§ 1.97 AND 1.98**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 15, 2004

Sir:

Pursuant to Applicants' duty of disclosure, and as a supplement to the Information Disclosure Statement dated October 18, 2004, enclosed please find English translations of Japanese Patent Document No. 2001-284463 and No. 2001-298095, submitted with the Information Disclosure Statement dated October 18, 2004. Note that an English abstract and specified figures of the above-identified Japanese patent documents were submitted with the Information Disclosure Statement submitted October 18, 2004.

Please note that in the enclosed English translation of No. 2001-298095, the expression of "6: silicon oxide film containing nitrogen" in Fig. 2 of the materials submitted on October 18, 2004 has been corrected to that of "6: silicon oxide film including nitrogen".

Also enclosed herewith is a replacement Form PTO/SB/08A, for the Form PTO/SB/08A filed with the Information Disclosure Statement dated October 18, 2004, and reflecting the present filing of the respective English translations.

This Information Disclosure Statement is being submitted subsequent to the filing of a Request for Continued Examination (RCE) Transmittal in the above-identified

application, but prior to issuance of a further Office Action after submission of such RCE Transmittal. Accordingly, it is respectfully submitted that requirements of 37 CFR § 1.97(b) are satisfied, with respect to the present submission of the enclosed English translations.

In view of the foregoing, it is respectfully submitted that all applicable requirements of 37 CFR §§ 1.97 and 1.98 have been satisfied, in connection with documents submitted with the respective Information Disclosure Statements submitted on October 18, 2004 and on even date. Accordingly, consideration of the documents submitted with these Information Disclosures Statements, upon further examination of the above-identified application, is respectfully requested.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to the Antonelli, Terry, Stout & Kraus, LLP, Deposit Account No. 01-2135 (Docket No. 501.42174VX1), and please credit any excess fees to such deposit account.

Respectfully submitted,  
ANTONELLI, TERRY, STOUT & KRAUS, LLP

By 

William I. Solomon  
Reg. No. 228,565 *WIS*

WIS/dlt

1300 North Seventeenth Street, Suite 1800  
Arlington, Virginia 22209  
Telephone: (703) 312-6600  
Facsimile: (703) 312-6666

PTO/SB/08A (10-01)

Examiner Signature		Date Considered	
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